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AF/2823
Docket No.: SON-2192
(PATENT)

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of:
Koji Kikuchi

Application No.: 09/939,773

Art Unit: 2823

Filed: August 28, 2001

Examiner: W. D. Coleman

For: MANUFACTURING METHOD OF A PHASE-SHIFT MASK, METHOD OF FORMING A RESIST PATTERN AND MANUFACTURING METHOD OF A SEMICONDUCTOR DEVICE

AMENDMENT AFTER FINAL ACTION (37 C.F.R. SECTION 1.116)

MS AF
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

In response to the Office Action dated April 29, 2004 (Paper No. 04272004), finally rejecting claims 1-10, please amend the above-identified U.S. patent application as follows: